

Comparative ellipsometric and ion beam analytical studies on ion beam crystallized silicon implanted with Zn and Pb ions

Lohner, Tivador; Angelov, Christo; **Mikli, Valdek** Thin solid films 2008 / 22, p. 8009-8012

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Raman scattering characterization of ion-beam synthesized Mg₂Si. 1, Influence of the technological conditions on the formation of the Mg₂Si in(100) Si matrix

Atanassov, Alexander; Zlateva, Genoveva; Baleva, Mitra; Goranova, Ekaterina; Amov, Blagoj; Angelov, Christo; **Mikli, Valdek** Plasma processes and polymers 2006 / 2, p. 219-223 : ill <https://onlinelibrary.wiley.com/doi/pdf/10.1002/ppap.200500088>

Study of ion implanted Fe depth distribution in Si after pulsed ion beam treatment

Angelov, Christo; Georgiev, S.; Amov, Blagoj; Goranova, E.; **Mikli, Valdek**; Dezs, I.; Kotai, E. Journal of optoelectronics and advanced materials 2007 / 2, p. 307-310

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